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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Zhang et al.
Serial Number: 10/696,326
Filed: October 29, 2003
Group Art Unit: 1756
Examiner: Unassigned
Title: *Photomask Assembly and Method for
Protecting the Same from Contaminants
during a Lithography Process*

EV352394655US

MAIL STOP - AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I hereby certify that this Information Disclosure Statement is being deposited with the United States Postal Service as Express Mail : EV352394655US addressed to: Mail Stop - Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on 11-1, 2004.


Angela Loding

INFORMATION DISCLOSURE STATEMENT

Applicants respectfully request, pursuant to 37 C.F.R. §§1.56, 1.97 and 1.98, that the references listed on the enclosed PTO-1449 form be considered and cited in the examination of the above-identified application. Applicants enclose a copy of the reference for the Examiner's convenience. Furthermore, pursuant to 37 C.F.R. §§1.97(g) and (h), no representation is made that this reference is material to the patentability of the present application.

Applicants believe no fees are due, however, the Commissioner is hereby authorized to charge any fees or credit any overpayments to Deposit Account No. 50-2148 of Baker Botts L.L.P.

Respectfully submitted,

BAKER BOTTS L.L.P.

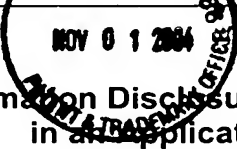
Attorneys for Applicants

A handwritten signature in black ink, appearing to read "Paula D. Heyman", with a long horizontal flourish extending to the right.

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Date: Nov. 1, 2004

PTO-1449		Application No. 10/696,326		Applicant(s) Zhang et al.			
 Information Disclosure Citation in an Application		Docket Number 064441.0266		Group Art Unit 1756	Filing Date 10/29/2003		
U.S. PATENT DOCUMENTS							
		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	A.						
	B.						
	C.						
	D.						
	E.						
	F.						
	G.						
	H.						
	I.						
	J.						
	K.						
	L.						
	M.						
	N.						
	O.						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
	P.						
	Q.						
NON-PATENT DOCUMENTS							
		DOCUMENT (Including Author, Title, Source, and Pertinent Pages)					DATE
	R.	Kishkovich, Oleg, et al., "Airborne Molecular Contamination Control for DUV Lithography", Cleanroom Technology, vol. 6(5), pp. 31-33.					June 2000
	S.						
	T.						
	U.						
EXAMINER					DATE CONSIDERED		
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.							